

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
Hiroshi TAKENO : **Mail Stop: PCT**  
Serial No. NEW : Attorney Docket No. 2004\_1129A  
Filed July 16, 2004 :

SILICON EPITAXIAL WAFER AND PROCESS FOR  
MANUFACTURING THE SAME  
[Corresponding to PCT/JP03/00345  
Filed January 17, 2003]

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**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**Prior to calculating the filing fee**, please amend the above-identified application as follows:

**Amendments to the Title**

**Please replace the title with the following new title:**

**SILICON EPITAXIAL WAFER AND PROCESS FOR MANUFACTURING THE  
SAME**

**Immediately after the title, please insert the following sentence:**

**This application is a U.S. national stage of International Application No.  
PCT/JP03/00345 filed January 17, 2003.**